

Electronic Patent Application Fee Transmittal

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|---|--|-----------------|---------------|-----------------------------|
| Application Number: | 10580036 | | | |
| Filing Date: | 19-May-2006 | | | |
| Title of Invention: | PLASMA PROCESSING METHOD AND PLASMA PROCESSING APPARATUS | | | |
| First Named Inventor/Applicant Name: | Yasuo Kobayashi | | | |
| Filer: | Marvin Jay Spivak/Sinee Samla | | | |
| Attorney Docket Number: | 291327US41PCT | | | |
| Filed as Large Entity | | | | |
| U.S. National Stage under 35 USC 371 Filing Fees | | | | |
| Description | Fee Code | Quantity | Amount | Sub-Total in USD(\$) |
| Basic Filing: | | | | |
| Pages: | | | | |
| Claims: | | | | |
| Miscellaneous-Filing: | | | | |
| Petition: | | | | |
| Patent-Appeals-and-Interference: | | | | |
| Post-Allowance-and-Post-Issuance: | | | | |
| Utility Appl issue fee | 1501 | 1 | 1510 | 1510 |
| Publ. Fee- early, voluntary, or normal | 1504 | 1 | 300 | 300 |

| Description | Fee Code | Quantity | Amount | Sub-Total in USD(\$) |
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| Extension-of-Time: | | | | |
| Miscellaneous: | | | | |
| Total in USD (\$) | | | | 1810 |